## ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Flectronic Version v18 Stylesheet Version v18.0

> Title of Invention

DIAPHRAGM VALVE WITH RELIABILITY ENHANCEMENTS FOR ATOMIC LAYER DEPOSITION

111,111,111,111,111

Application Number :

10/609339

Confirmation Number: First Named Applicant:

9277 Jarmo Maula

Attorney Docket Number: 11429/13:3

Art Unit:

Examiner:

Search string:

( 5520001 or 6752387 or 20030121608 ).pn

## **US Patent Documents**

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	5520001	1996-05-28	Miyamoto et al.		62	50.2
	2	6752387	2004-06-22	Nishizato et al.	B1	261	62

## **US Published Applications**

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init	Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
	1	20030121608	2003-07-03	Chen et al.	A1	156	345.33

## Signature

Examiner Name	Date